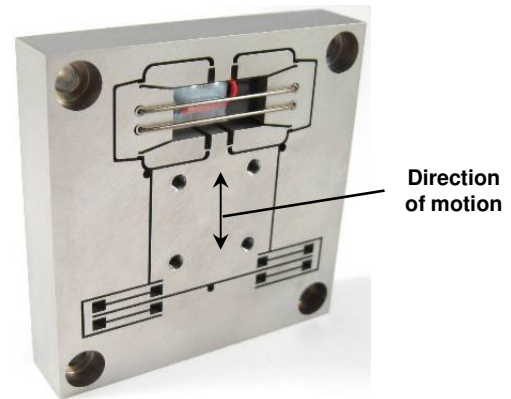


XSA-0200C: 200 micron Nanopositioning Stage

Description

DSM's nanopositioning piezoelectric XSA-0200C stage features flexure-guided motion over a 200 micron travel range for scanning, metrology, and inspection processes. The stage's stable and stiff kinematic design promotes parallelism in the output motion with minimal pitch and yaw as well as dynamic responsiveness for excellent position stability and control.

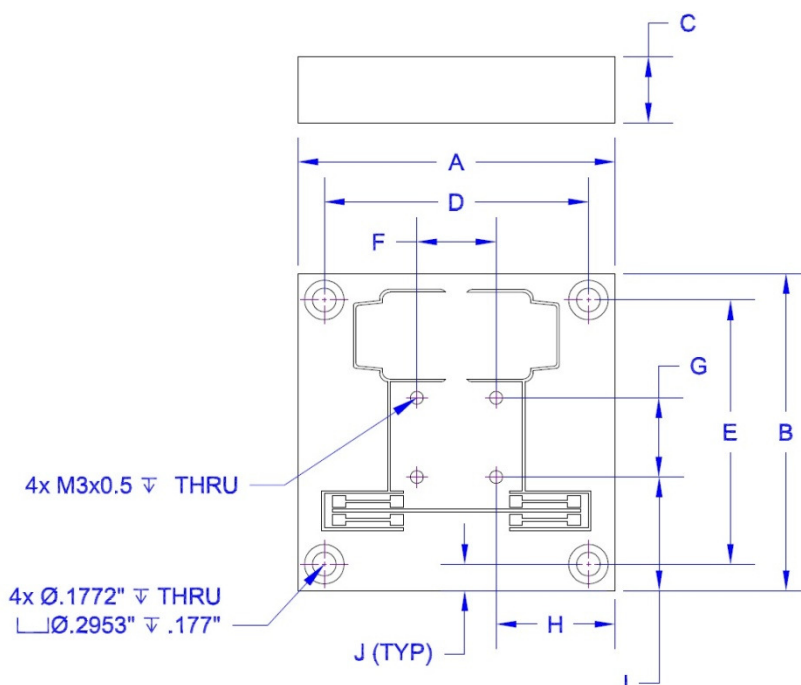


Specifications

- Open-Loop Travel: 200 micron \pm 10%
- Stiffness: 0.8N/micron \pm 10%
- Linearity: 0.12% typical
- Pitch / Yaw: <20 micro radians typical
- Unloaded Resonant Freq: 420 Hz \pm 10%
- Blocking Force: 160 N \pm 10%
- Push/pull force capacity: 40 N Max
- Electrical Capacitance: 3.6 micro Farads \pm 10%
- Operating Temp Range: -20 to 80 degrees Celsius
- Operating Voltage: -30 to 150 V
- Dimensions: 60 x 60 x 12.5 mm
- Mass: 0.31 kilogram \pm 10%
- Material: Stainless steel
- Cable Length: Flying Leads (Options Available)

Highlights of the X-Stage Design

- Flexure guidance provides smooth, parallel motion with no backlash
- Stiff construction for responsive dynamic behavior
- Customizable mounting configurations



Dim	(mm)	(in)
A:	60	2.4
B:	60	2.4
C:	12.5	0.5
D:	50	2
E:	50	2
F:	15	0.6
G:	15	0.6
H:	22.5	0.9
I:	21.5	0.8
J:	5	0.2